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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : **Confirmation No. 1632**
Norio KIMURA et al. : Docket No. 2001-0660A
Serial No. 09/864,208 : Group Art Unit 1763
Filed May 25, 2001 : Examiner Sylvia MacArthur

SUBSTRATE POLISHING APPARATUS
AND SUBSTRATE POLISHING METHOD

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AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

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Sir:

In response to the Office Action of June 26, 2003, the period for response to which having been extended by one month to October 26, 2003, kindly amend the above-referenced U.S. patent application as follows:

10/07/2003 CCHAU1 00000009 09864208

03 FC:1202 72.00 OP
04 FC:1201 86.00 OP

AMENDMENTS TO THE SPECIFICATION AND ABSTRACT

Please replace the original specification and abstract with the enclosed substitute specification and abstract. No new matter has been entered.